



life.augmented

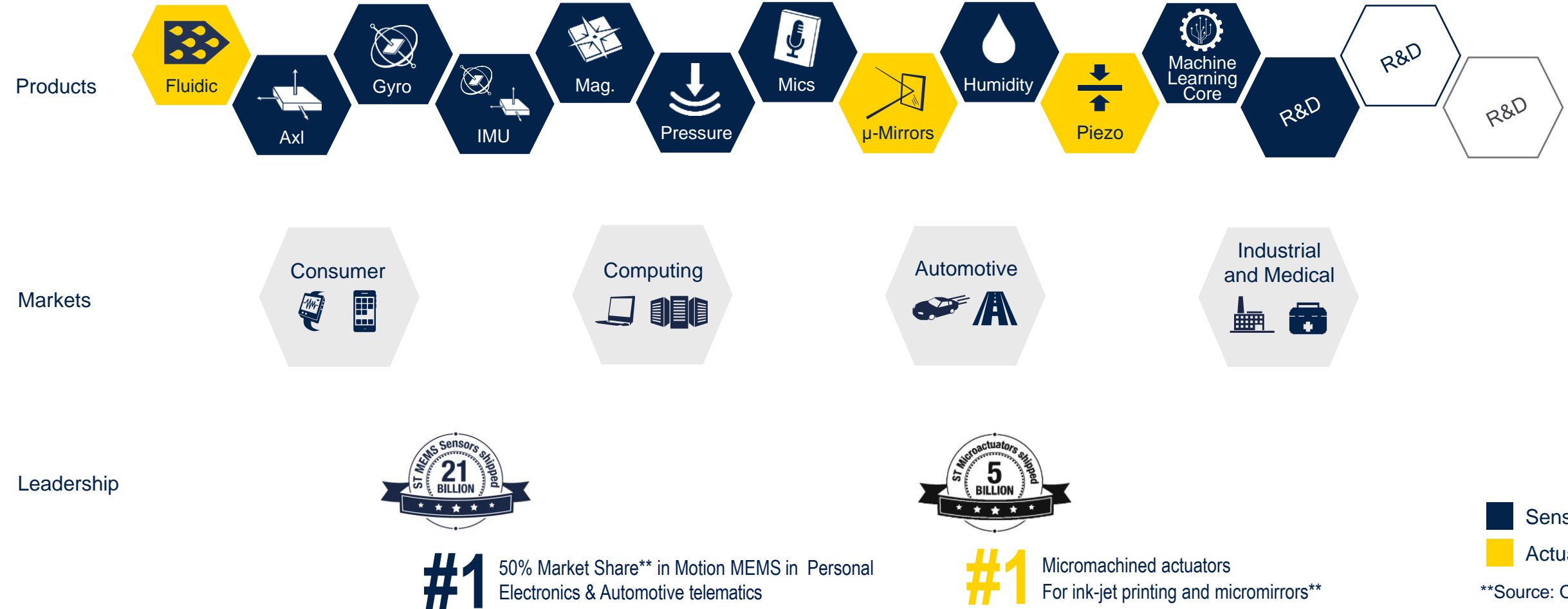
Laser Beam Scanning for Augmented Reality Wearable Applications

12th October 2022, ST Developers Conference

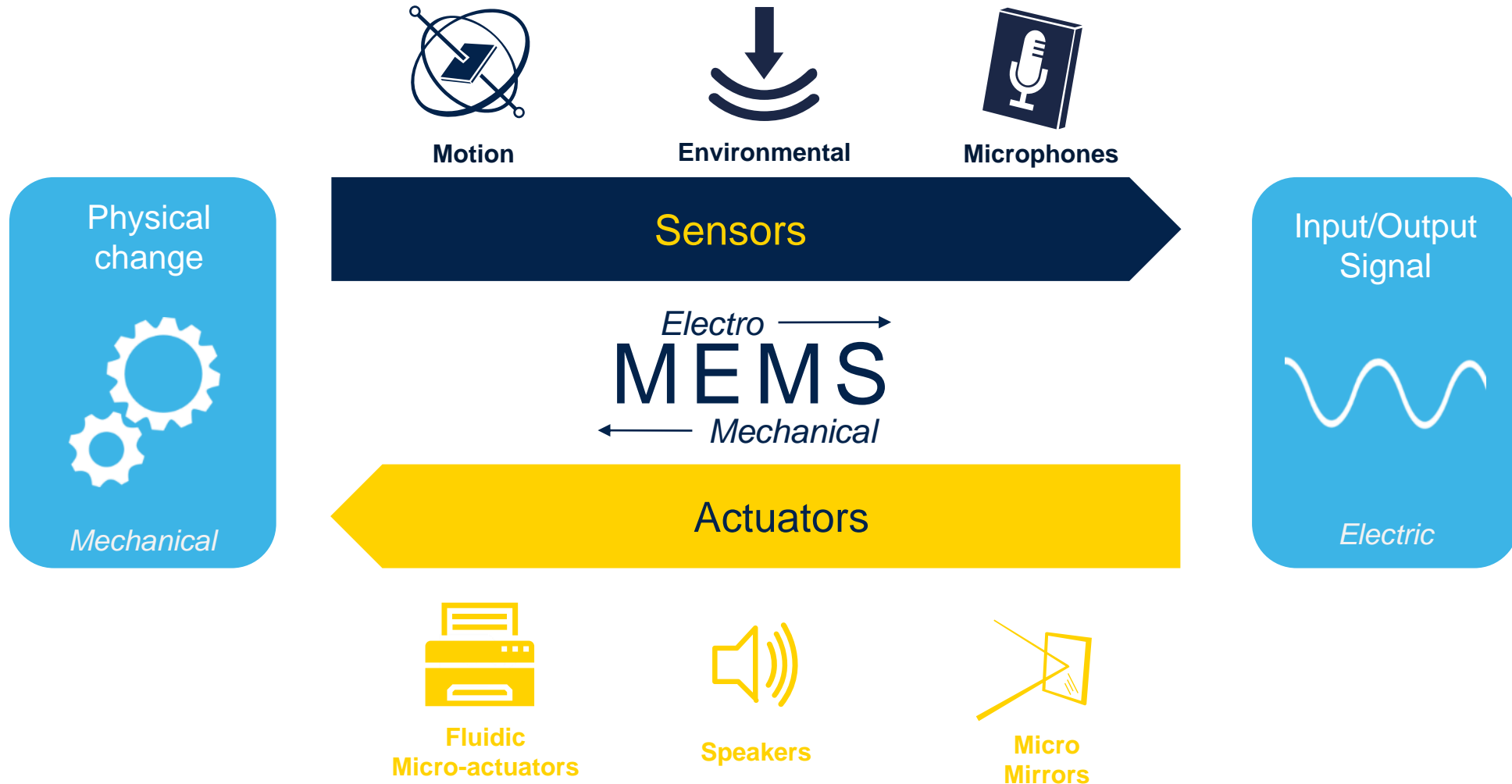
MEMS Product Marketing

Nicolò BONI

20 Years and 26 Billion of MEMS at ST



Sensing and Actuating



Sensors vs Actuators

Actuators need to “change” the external environment:

Large force needed → actuators are typically larger than sensors

ACTUATOR
MEMS only



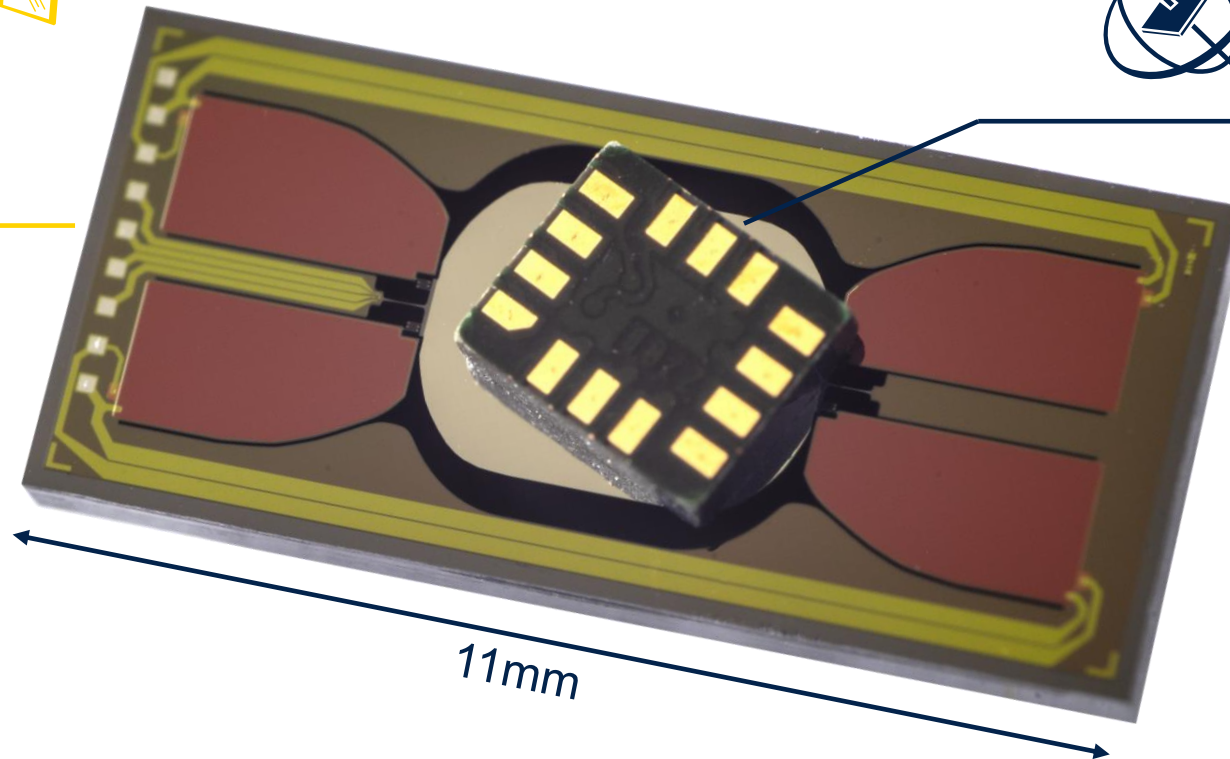
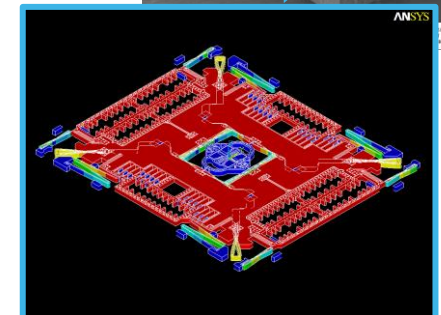
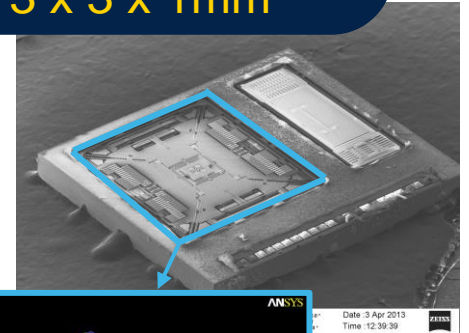
11 x 5 x 1mm



SENSOR
2xMEMS + ASIC
In package



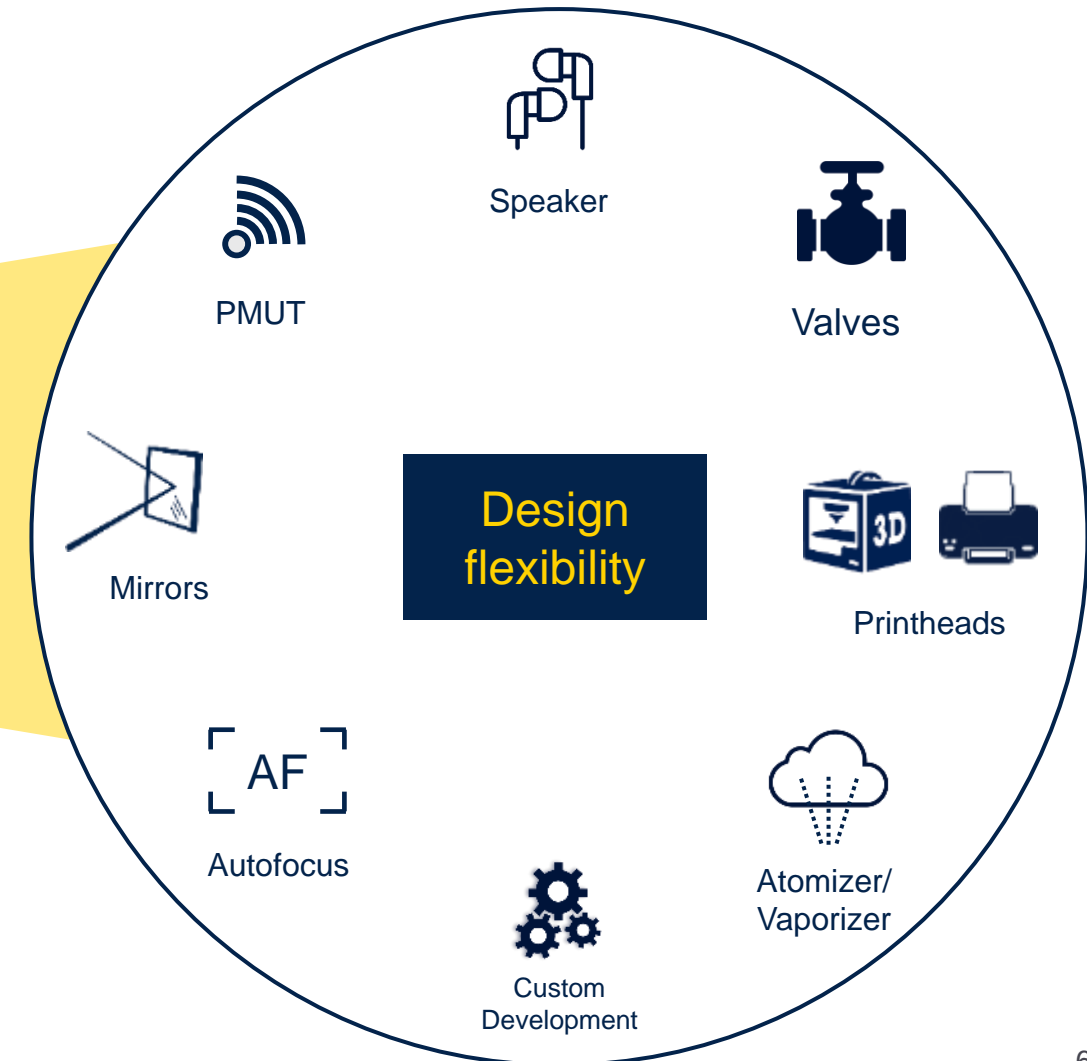
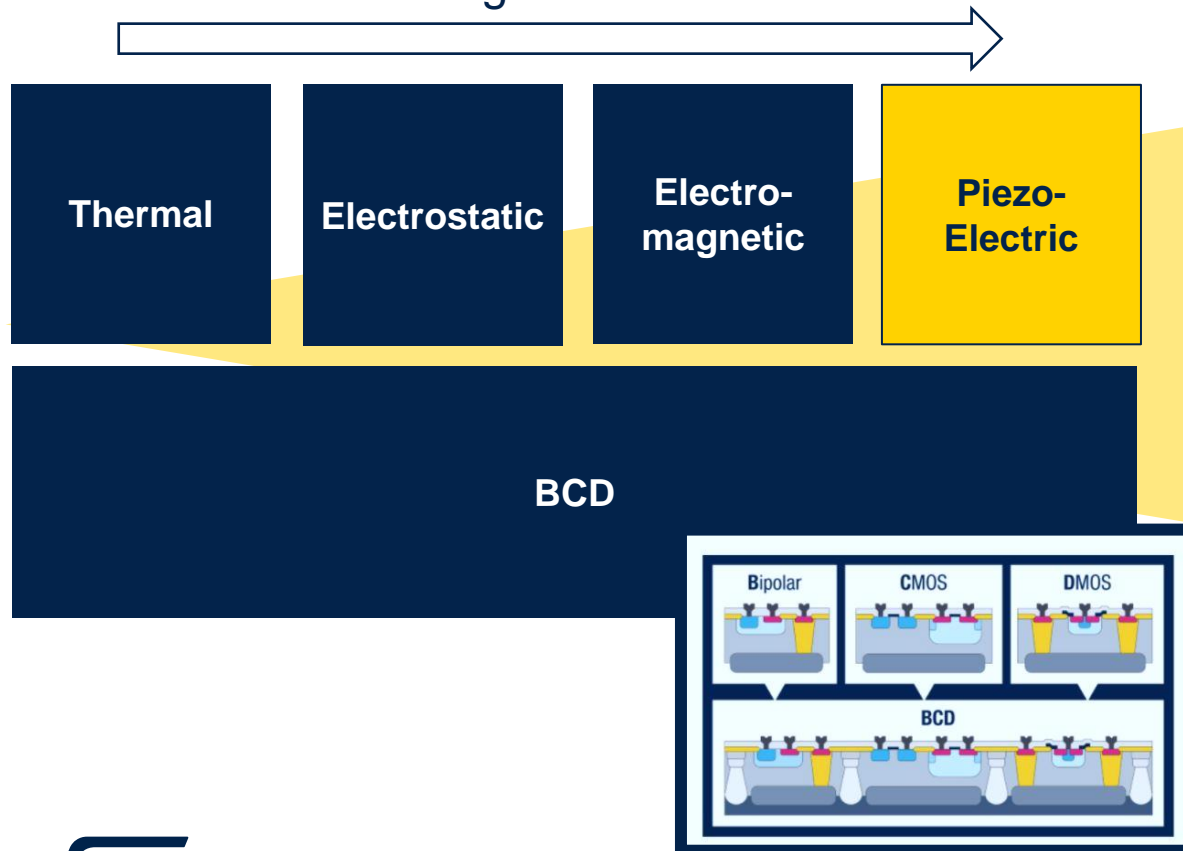
3 x 3 x 1mm



Microactuators Technologies and Lab-in-Fab

Micro-actuators: Technologies and Products

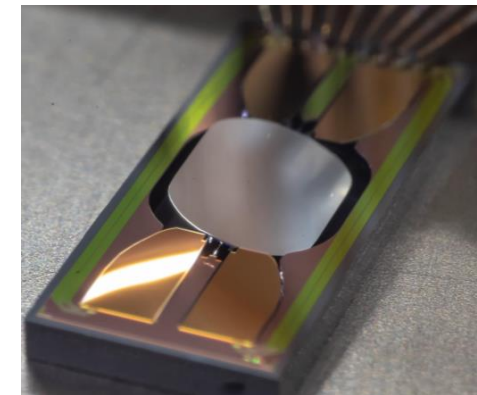
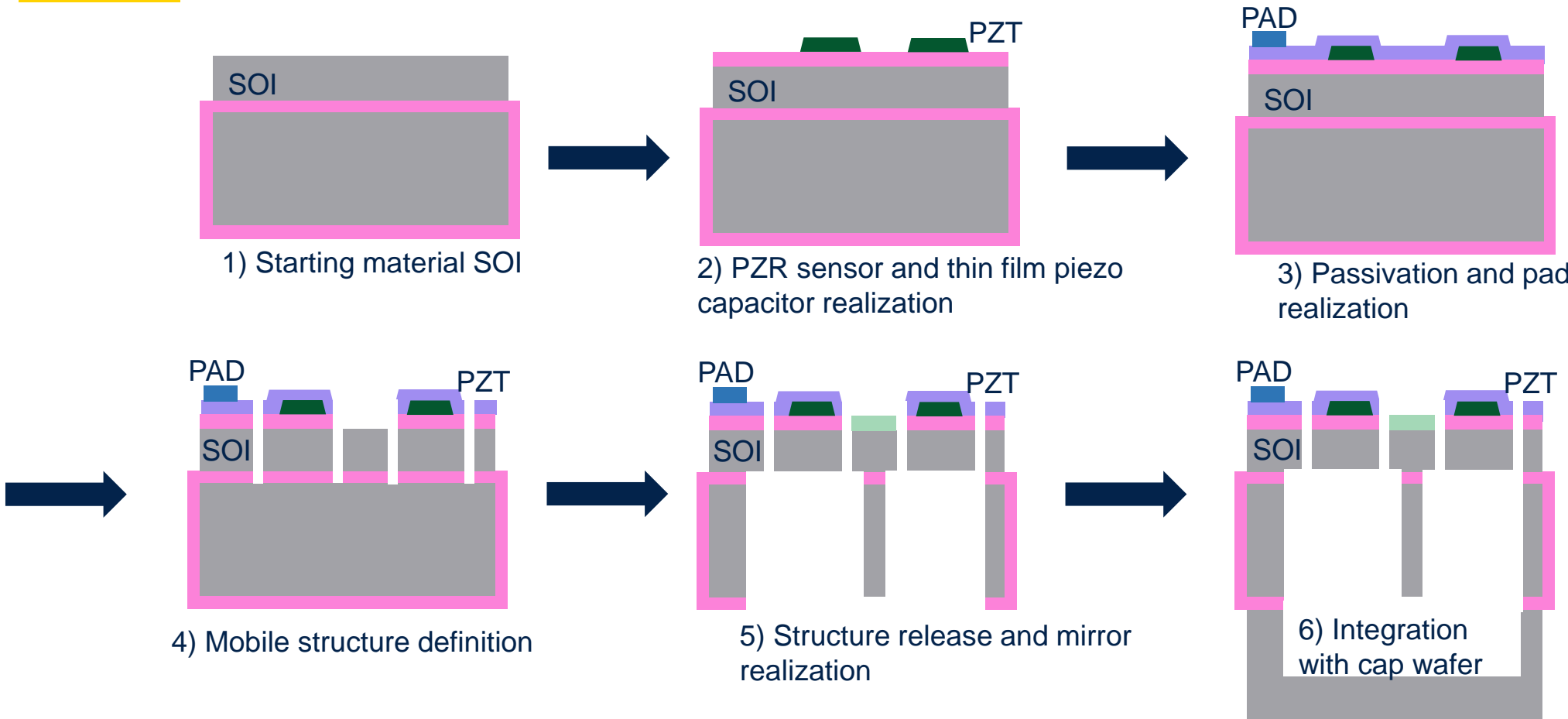
Different technologies for MEMS actuators



PεTRA Technology



- ST developed **PεTRA** technology platform to create PZT-based MEMS actuators



World's first “Lab-in-Fab” on Piezo MEMS



New MEMS R&D line hosted at ST's Singapore campus

R&D tools and engineers co-located by the participating parties

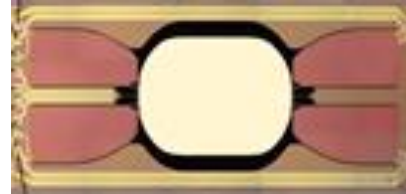
Embedded in ST's Fab to enable fast time to volume

Mission: become the world's leading R&D center for Piezo MEMS, from fast POC to manufacturing

PεTRA Technology - Roadmap

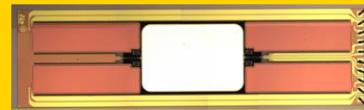
Sol-Gel

2018 Mass production
8" sol-gel PZT
process



First fully industrialized process for
multiple applications

2021 Improved doped
PZT process
(e31f ↑)

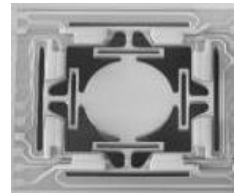


STAR1 – MEMS mirrors

Doped PZT to improve actuation force

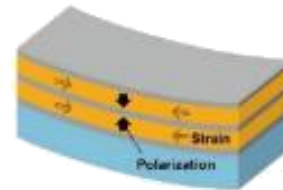
PVD

2022 PVD PZT
(e31f ↑ ↑)



Optimal flexibility and lower
manufacturing cost

2024 Multilayer PVD PZT



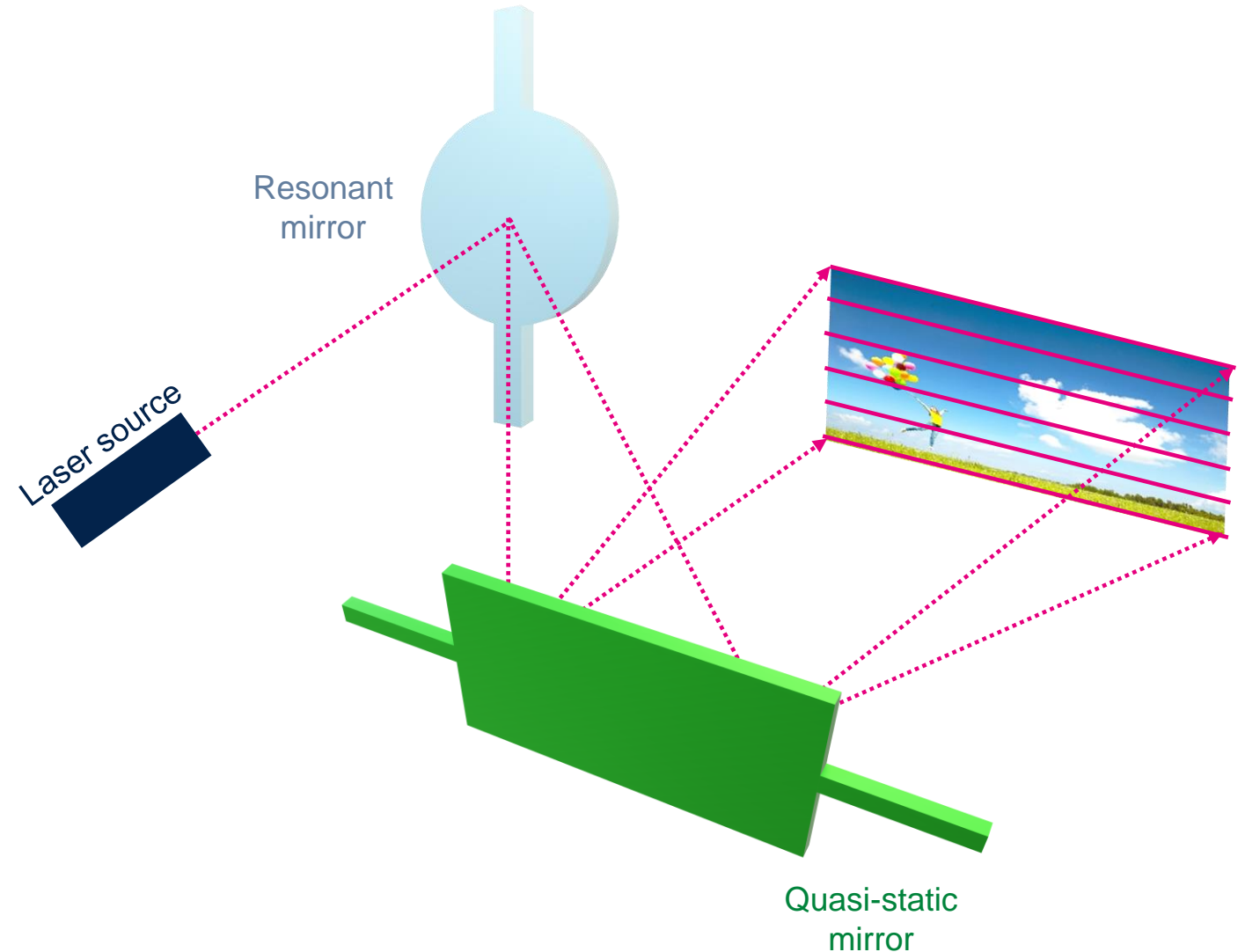
Actuation force increase by layer
stacking for power and area reduction

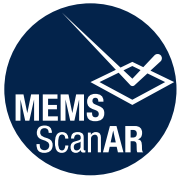
MEMS Micromirrors

MEMS Mirrors: Laser Beam Scanning

Principles:

- Light from one/multiple **lasers** is combined into a single beam
- Beam is relayed onto **MEMS scanning mirror(s)**
- Mirror(s) scan the beam in a **raster** pattern





Micro Mirrors: Laser Beam Scanning Applications

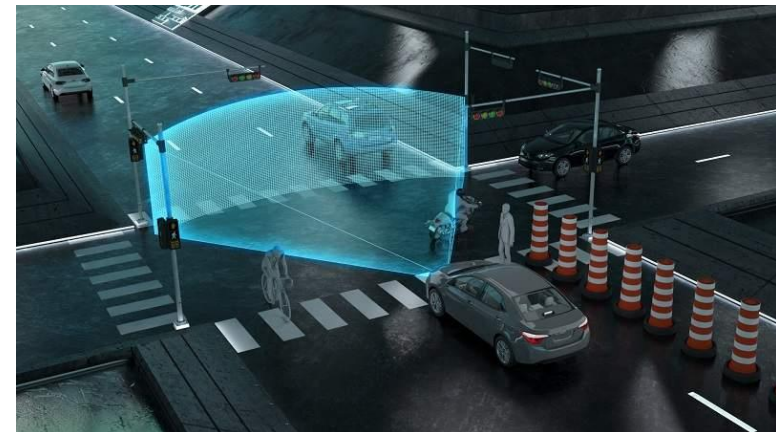
Projection (visible light):

Smart Glasses and Augmented/Mixed Reality (xR)



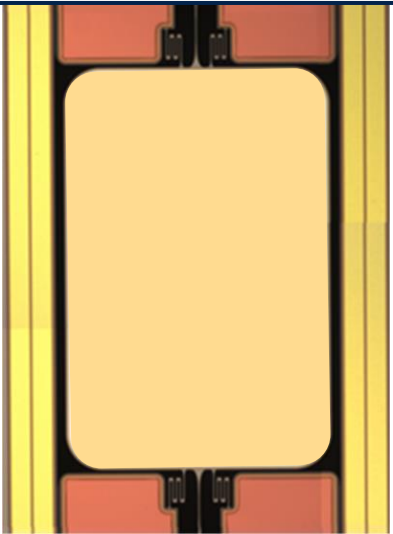
Sensing (typically infrared light):

3D Mapping (ex. industrial LiDAR or 3D camera)
Automotive LiDAR and Advanced Driver Assistance Systems

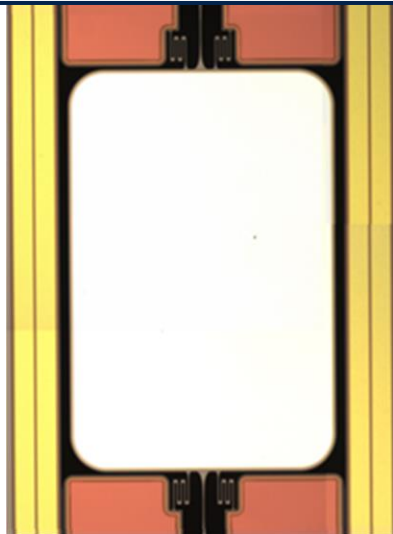


Optical Surface – Mirror Coating

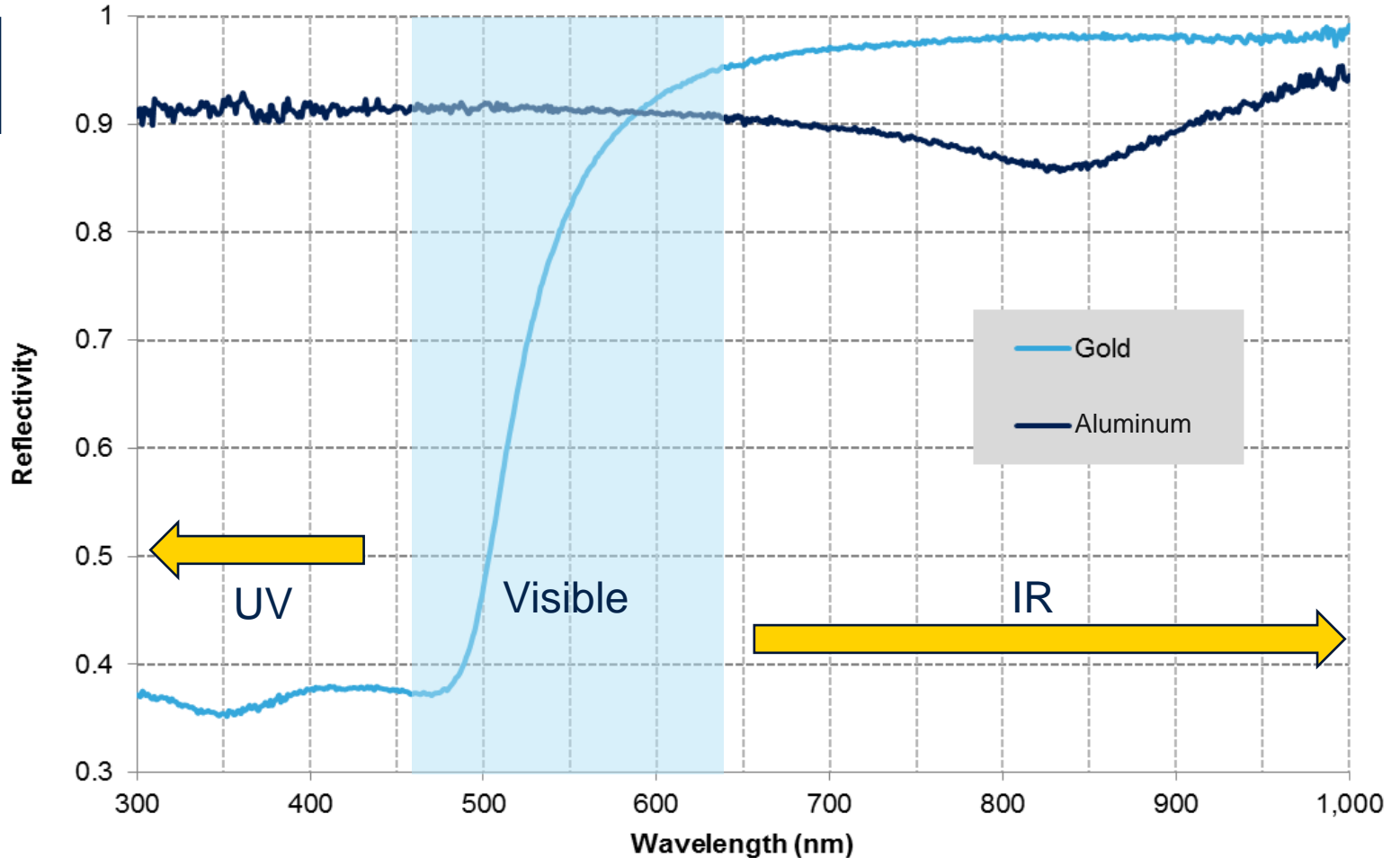
Gold coating →
infrared projection



Aluminum coating →
visible projection



Both coatings can be integrated on the same mechanical structures looking for the best performance in the target application.



MEMS Micromirrors for XR

XR: Augmented and Mixed Reality



Source: North

AR glasses:

Small
Lightweight
All day



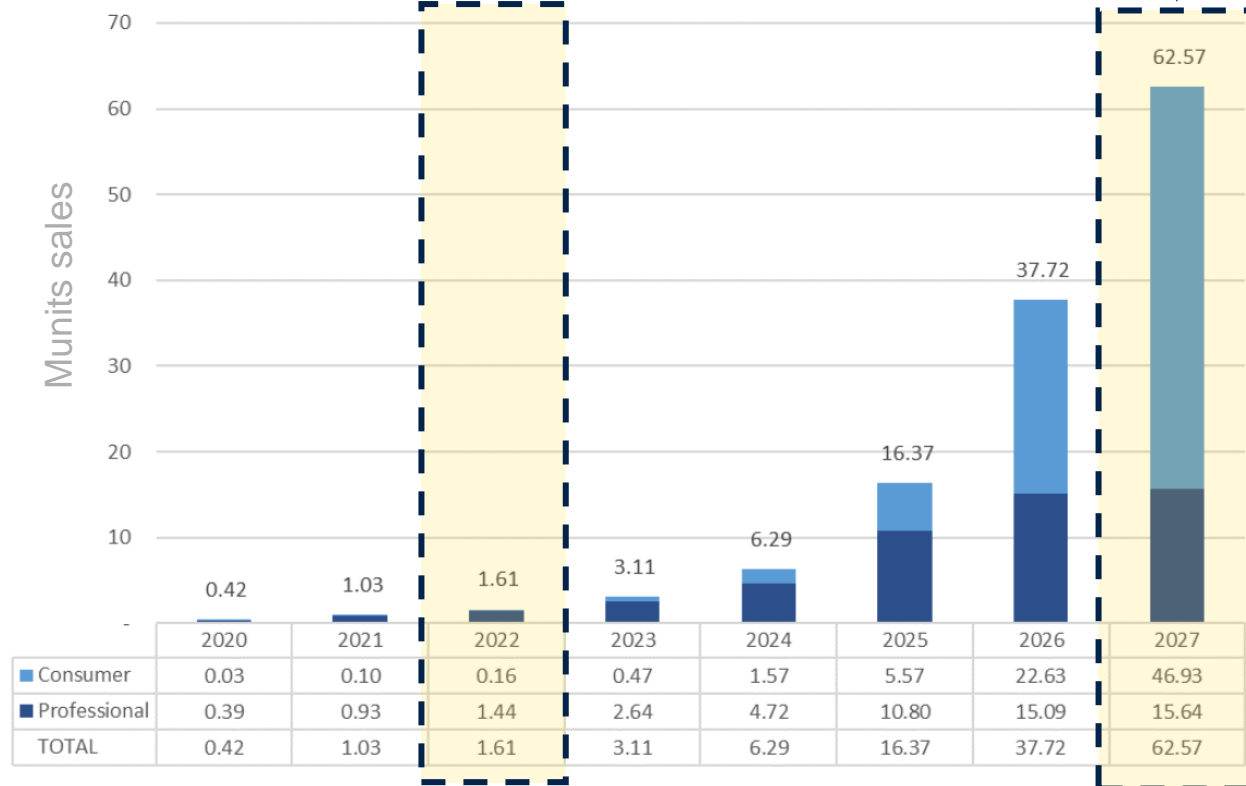
Source: Microsoft

MR glasses:

High resolution
Immersive
Powerful



AR and MR headsets sales:
1Mu to 60Mu in 5 years

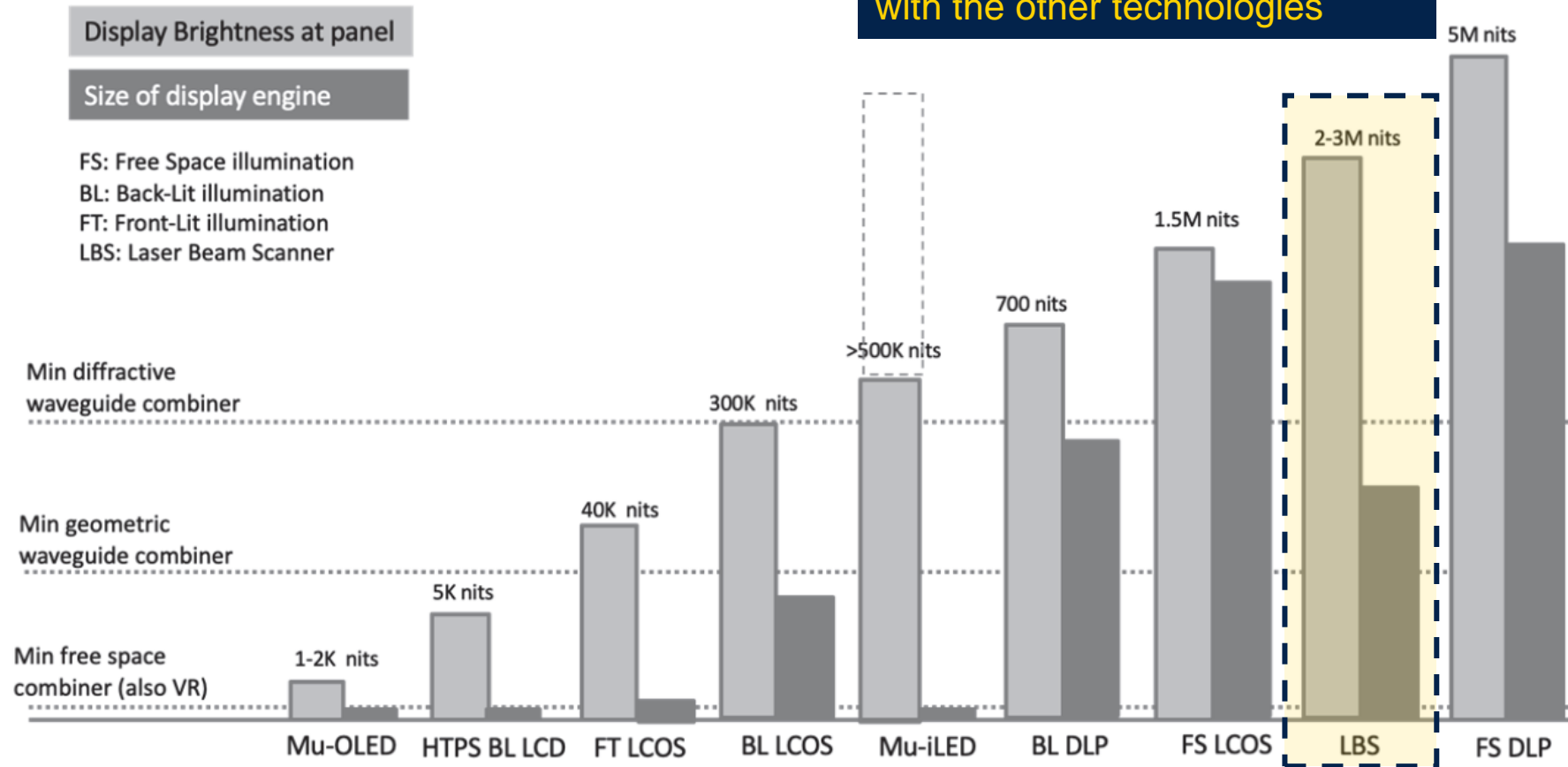


Source: Yole Displays & optics for AR &VR 2022

XR Glasses: Why Laser Beam Scanning?

LBS has the best brightness to volume ratio (nits/cc) compared with the other technologies

Enabling truly lightweight, all-day smart glasses

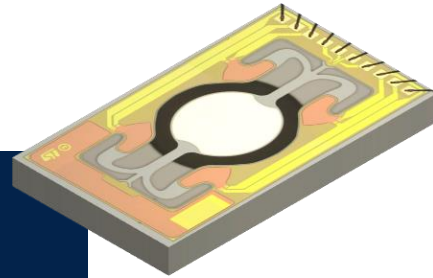


STAR1 MEMS Mirrors

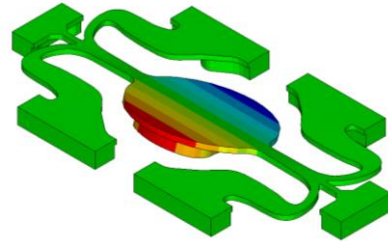
MMR40100 - Castor

- Resonant Mono-Axial
 - P ϵ TRA™ TF PZT material
- Aluminum Coating
- PZR Position Sensing

- 56° Optical Field-of-View
- 1.1mm Diameter Mirror
- 27.5 kHz Resonant Freq.
- $\pm 14^\circ$ Mechanical Angle
- 4.0 x 2.4 mm² Die size



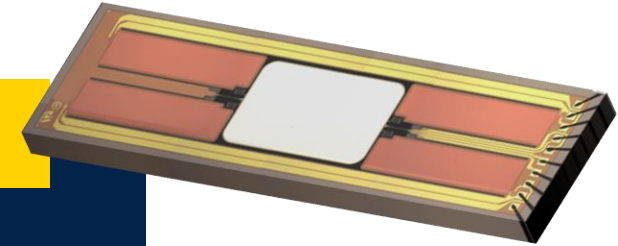
Eng. samples
available now



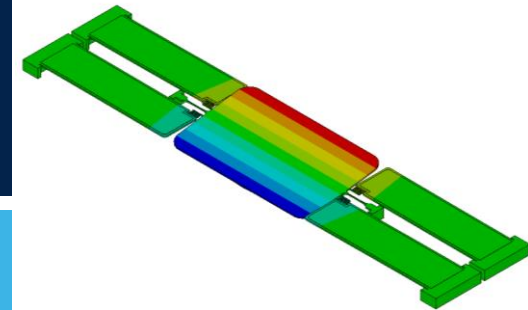
MML40100 - Pollux

- Linear Mono-Axial
 - P ϵ TRA™ TF PZT material
- Aluminum Coating
- PZR Position Sensing

- 32° Optical Field-of-View
- 2.45 x 1.44 mm² Mirror
- Up to 250 Hz Refresh Rate
- $\pm 8^\circ$ Mechanical Angle
- 7.5 x 2.3 mm² Die size

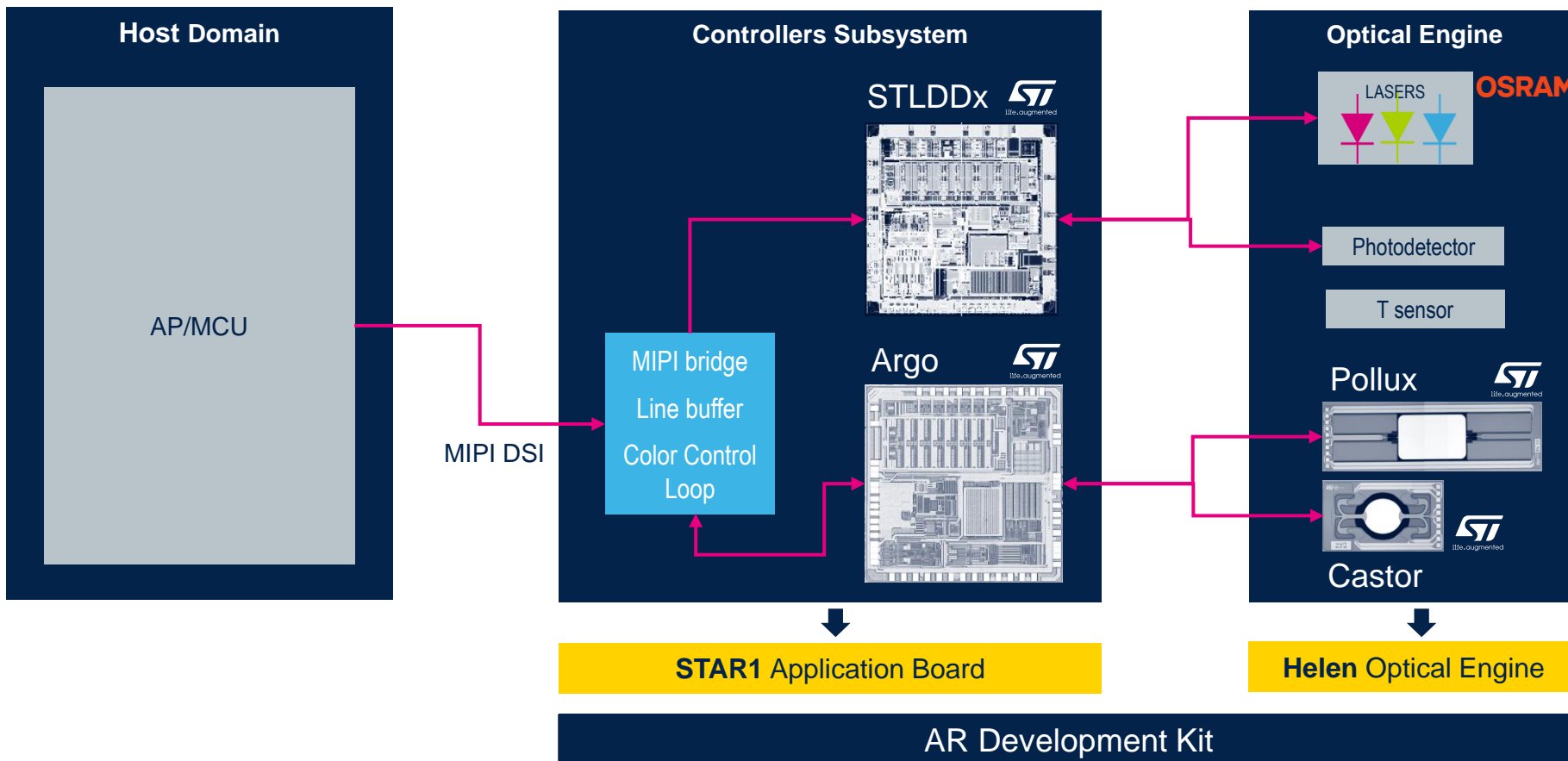


Eng. samples
available now



STAR1 development kit for XR applications

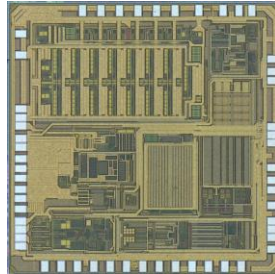
Based On ST Piezo Mirror Technology



MMD40100 - Argo

- Linear / Resonant Driver
- Configurable HW Control Loops:
 - Resonant Mirror
 - Linear Mirror
- Integrated Safety Mechanism
- Embedded Environmental Compensation

- Low Power Consumption
- Energy Charge Recovery
- Compact Dimensions
 - BGA 5 x 5 x 1 mm³ package

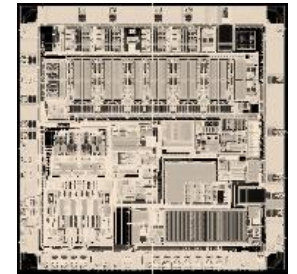


Eng. samples
available now

STLDDx

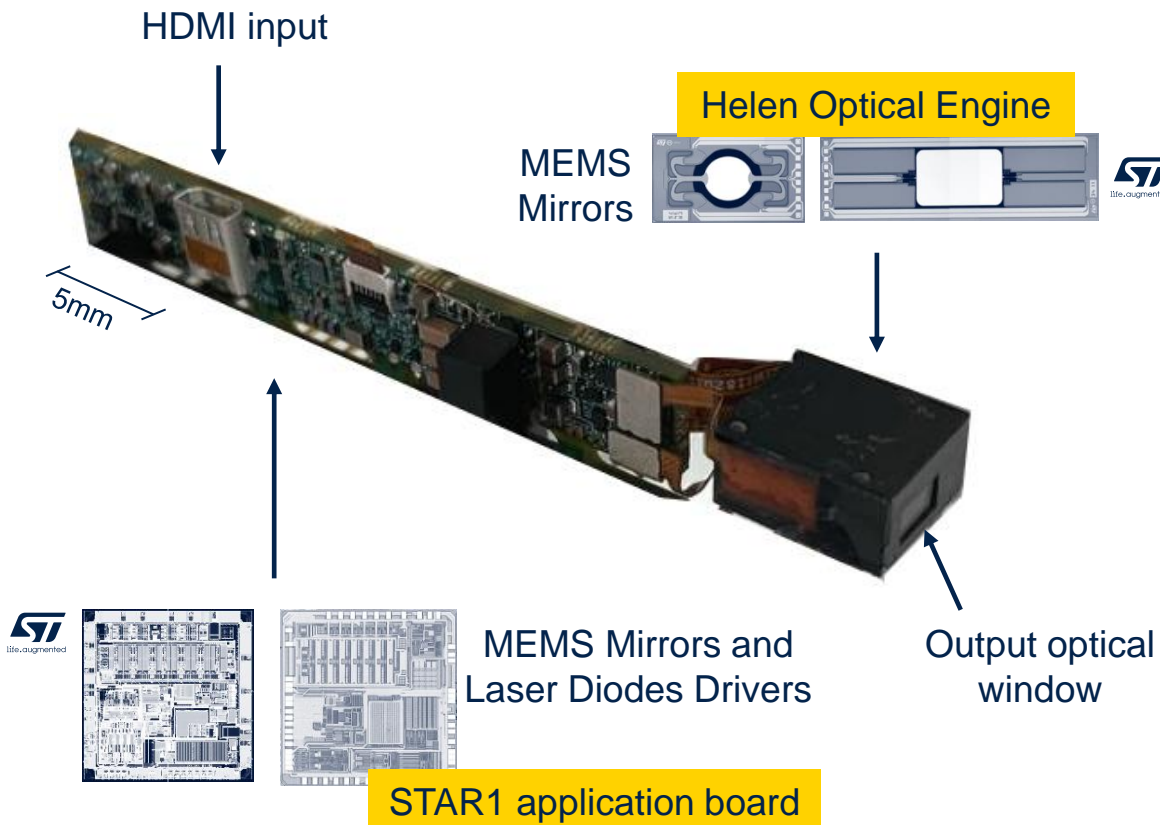
- Laser Diode Driver
- 2 Device Options:
 - Up To 4 Laser Diode Drive Channels
- Low-power Mode:
 - Automatically Triggered Based On Input Pixel Data

- 500 ps Rise / Fall Time
- Up to 260MHz Pixel Rate
- Compact Dimensions
 - <20 mm² (WLCSP)



Eng. samples
available now

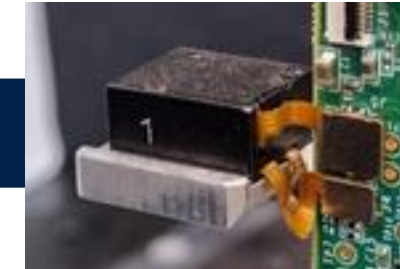
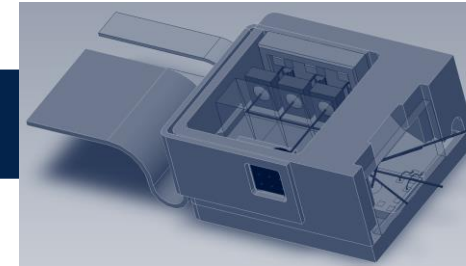
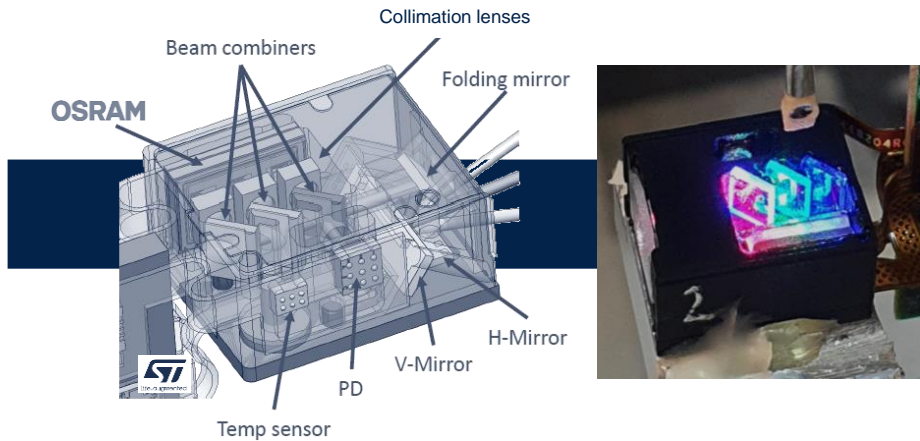
STAR1 Laser Beam Scanning



STAR1 Dev Kit– Main features:

- Complete projection system (HDMI input)
- Volume occupation: **<0.7cc** optical engine
- Optical FOV: up to **65deg**
- Output brightness: **1.5-10 lumens**
- Resolution: **720p**
- System power consumption: **~350mW**

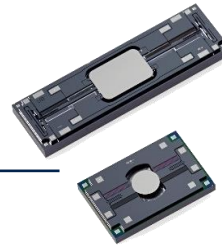
ST LBS Optical Engine: Roadmap



STAR0 → Electrostatic Mirrors

Optical Engine for STAR0

Helen OE FoV (Diag)	56°
Output Brightness	1.5 – 10 lm
Resolution	960 x 600p
Size	0.75 cc
MEMS Mirrors	Electrostatic

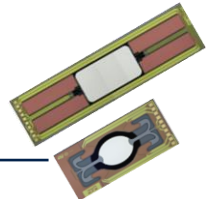


700mW power
consumption

STAR1 → Piezoelectric Mirrors

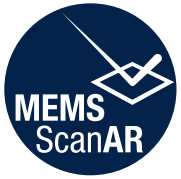
Optical Engine for STAR1

OE FoV (Diag)	65°
Output Brightness	1.5 – 10 lm
Resolution	1280 x 720p
Size	< 0.7 cc
MEMS Mirrors	Thin Film Piezo



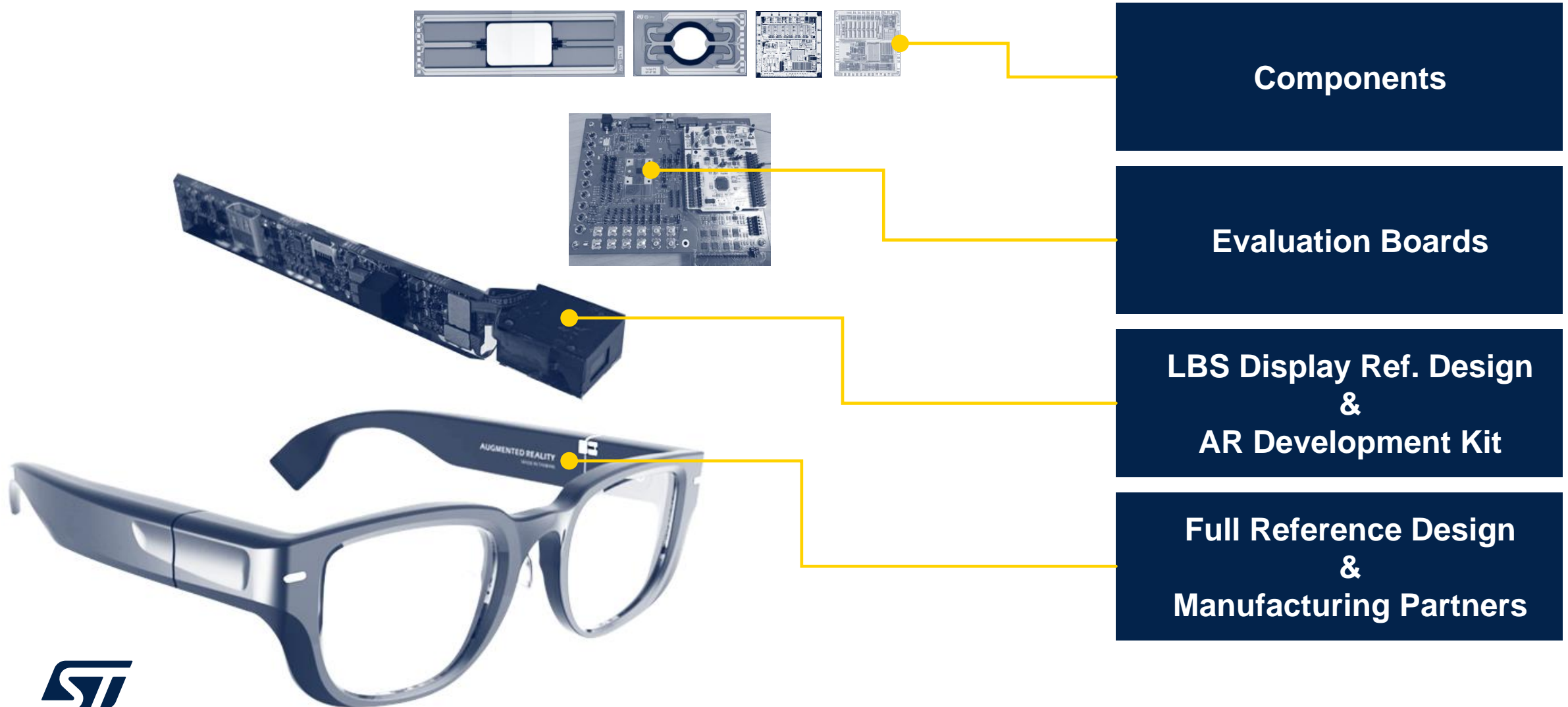
350mW power
consumption





Laser Beam Scanning Solutions

for fast development of high-performance Augmented Reality applications



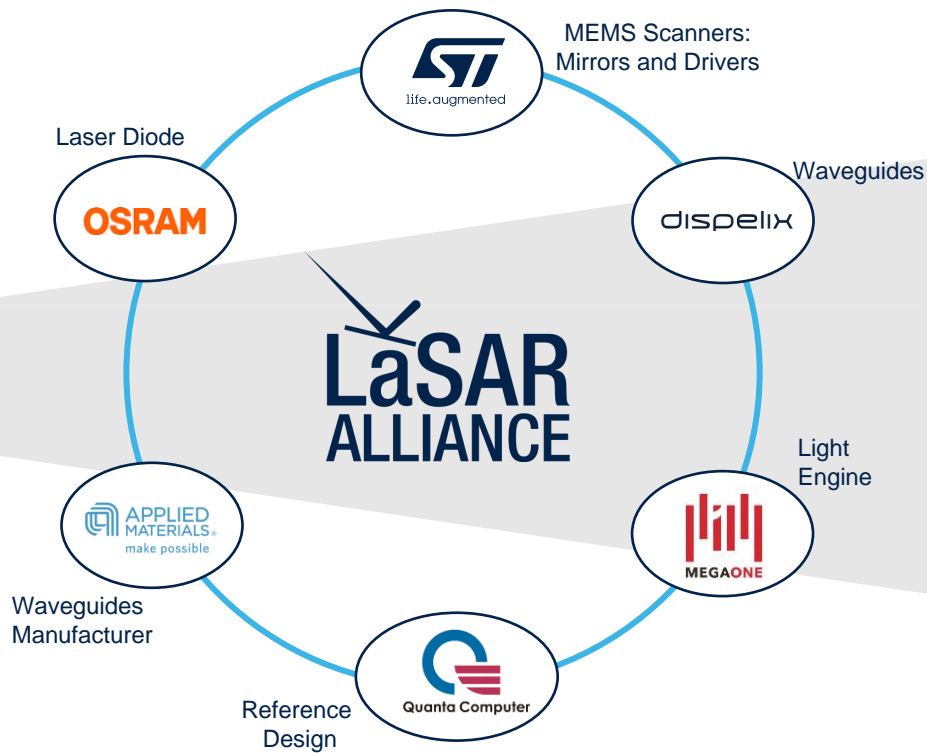
LaSAR

is an acronym for

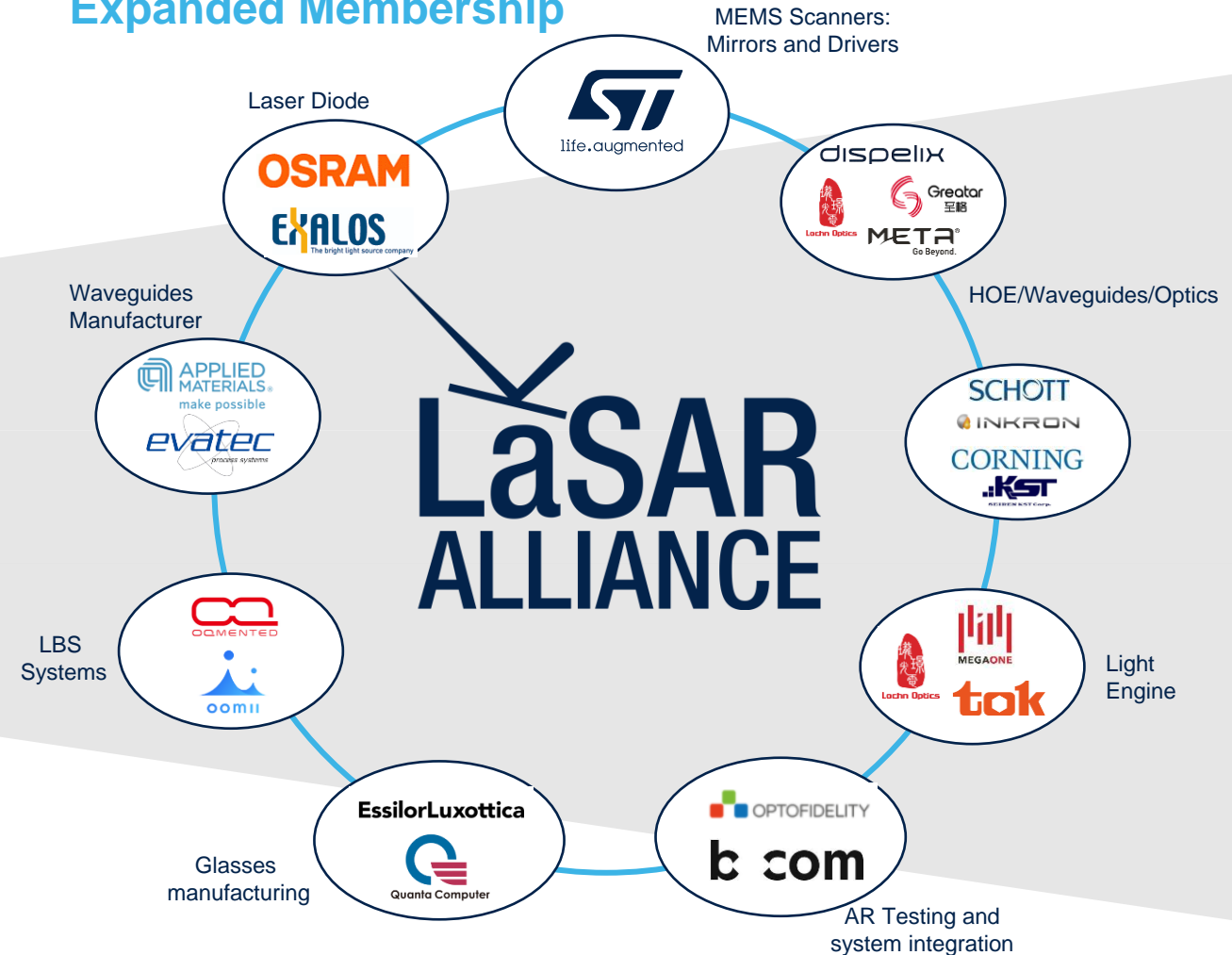
Laser **S**canning
for **A**ugmented **R**eality

The LaSAR Alliance Ecosystem

Founding Members



Expanded Membership

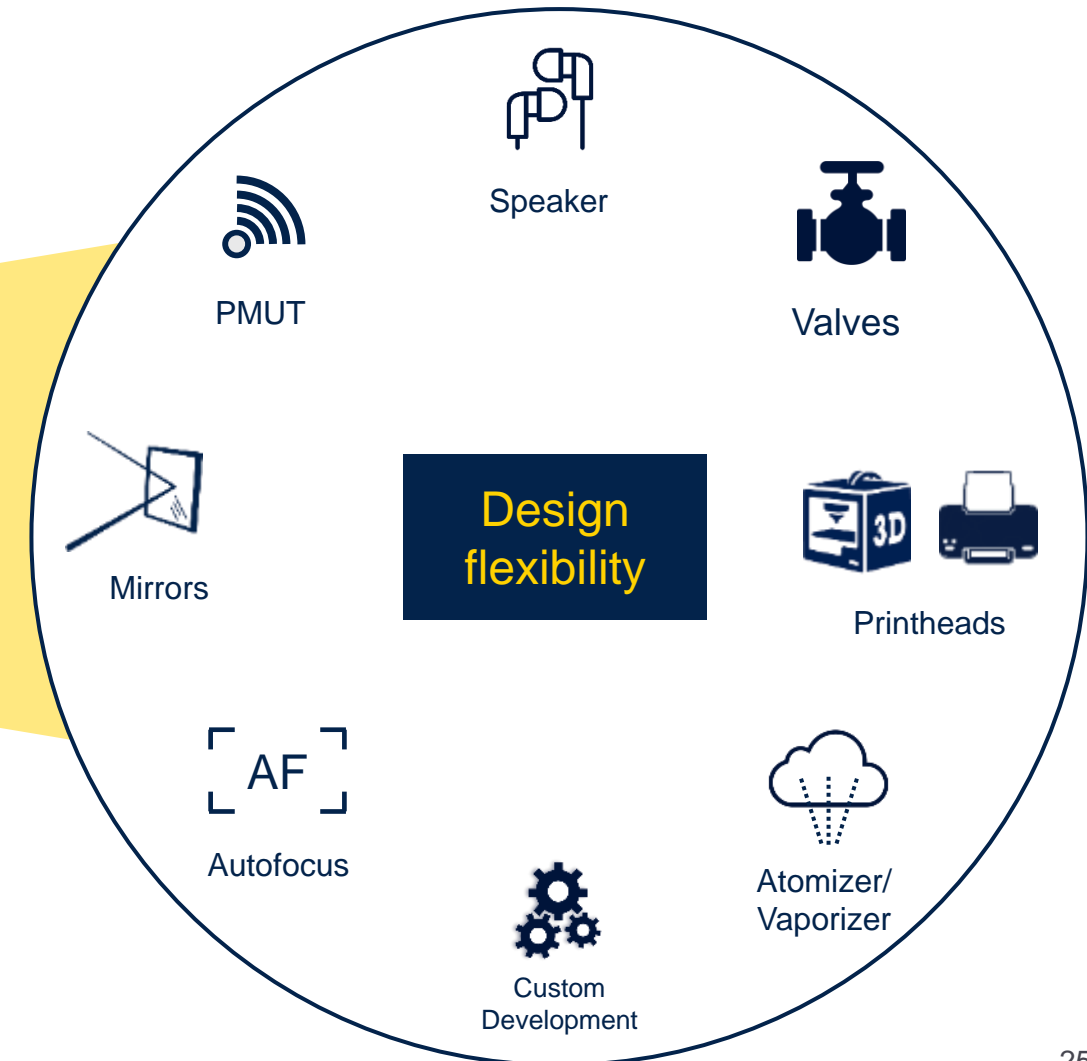
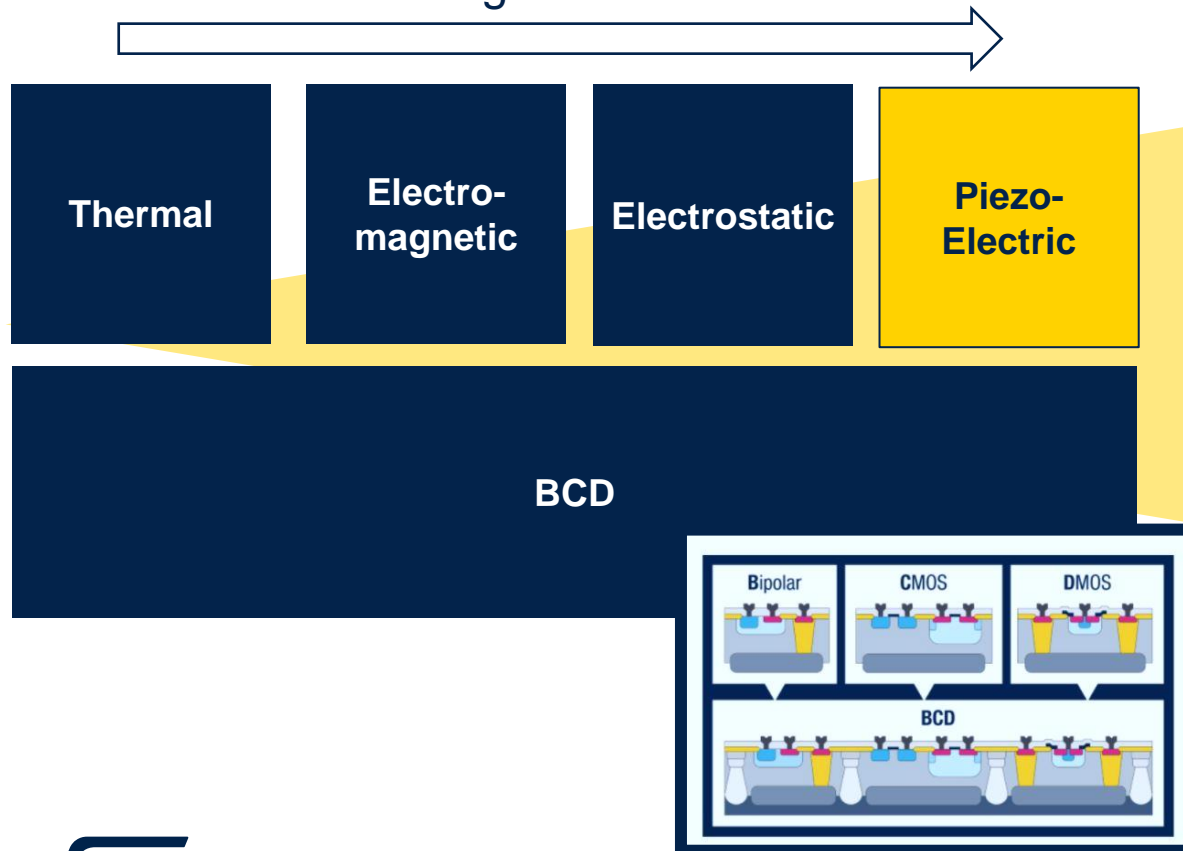


Strategic partners for mass production

Other piezo actuators

Micro-actuators: Technologies and Products

Different technologies for MEMS actuators



MEMS Autofocus Lens - PoLight



- **Working principle:**

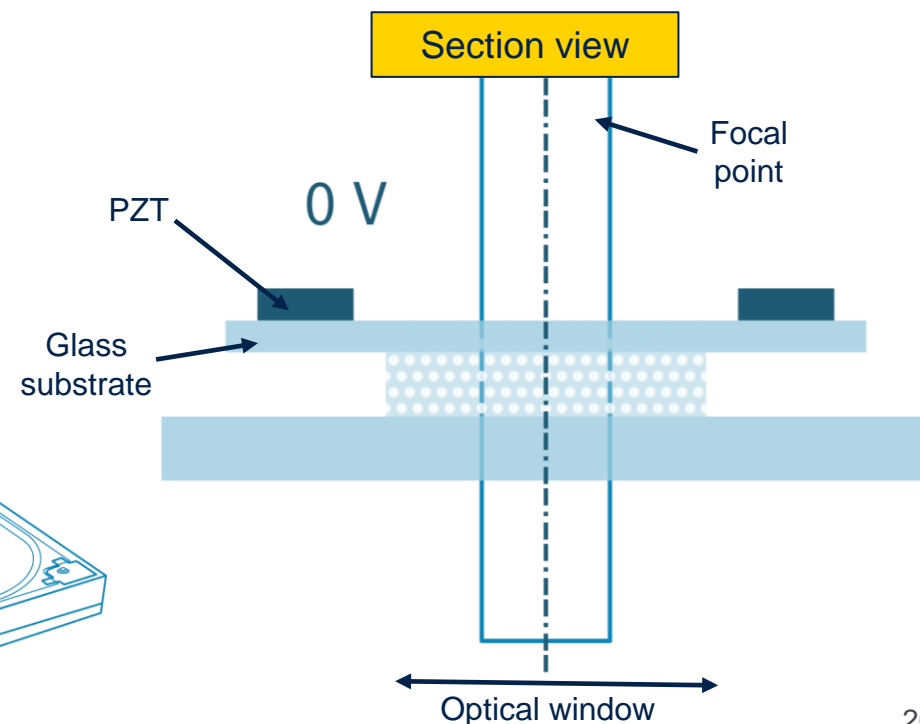
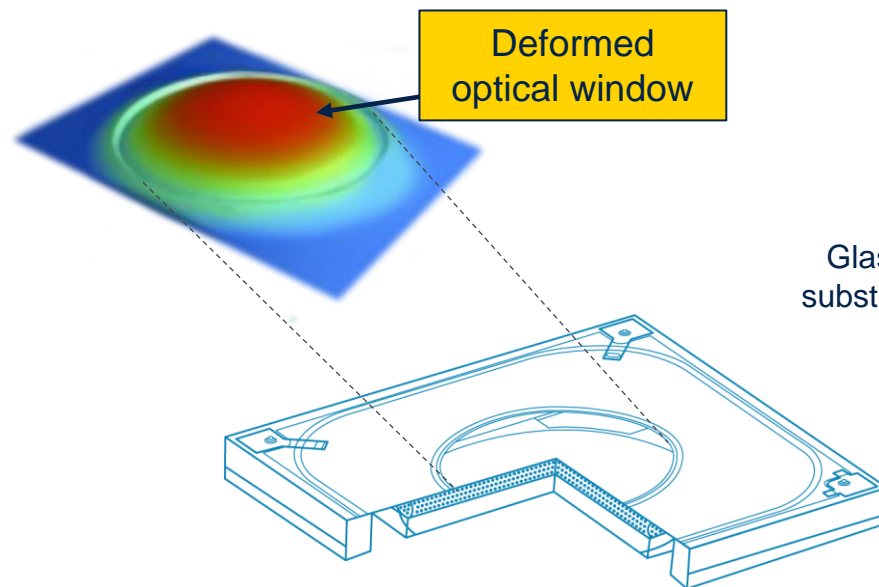
- PZT actuation used to deflect a glass substrate
- Changing the driving voltage, the deformation changes and so the focal point of the lens
- The MEMS has been developed in partnership with Polight



Source: Polight



life.augmented



Ultrasounds - PMUT



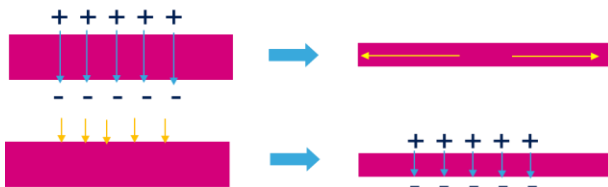
- **PMUT: Piezoelectric Micromachined Ultrasonic Transducer**

- **Ultrasound wave used to scan the environment:** actuator and sensor embedded in the same device

Piezoelectric

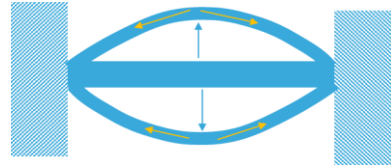


Inverse piezoelectric effect



Direct piezoelectric effect

Mechanical



Mechanical forces ↔ Deformation

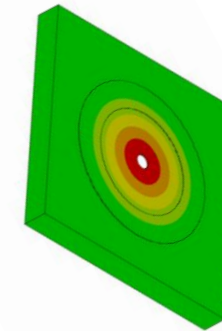
Acoustic



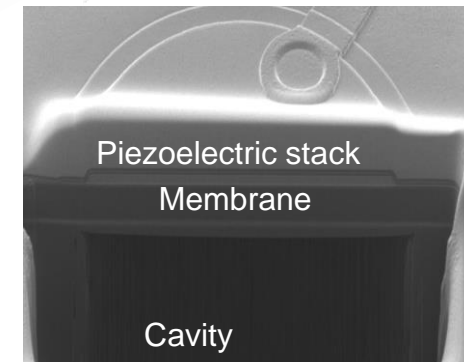
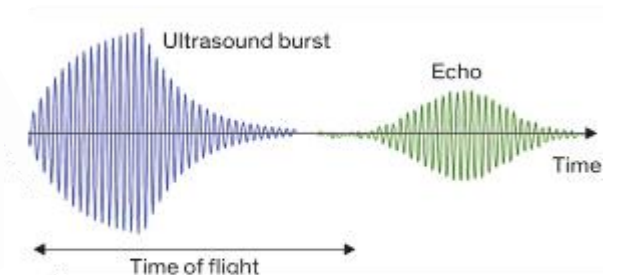
Transmission

Reception

Three physical domains in one device, based on piezoelectric thin-film layer technology



PMUT



PMUT – Applications

Consumer

Fingerprint
Sensing

Proximity
Sensing

User Interaction
Gesture Rec.

Automotive

Battery
Monitoring

User Interaction
Gesture Rec.

Industrial

Non-Destructive
Testing

Measurement &
Automation

Medical

Ultrasound
Imaging

Therapeutic
Ultrasound

Wearable
Monitoring

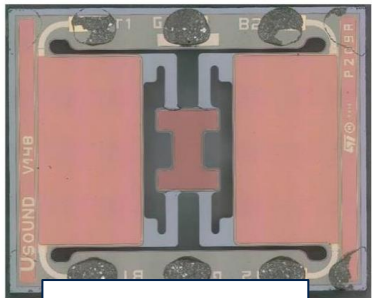


MEMS Speakers

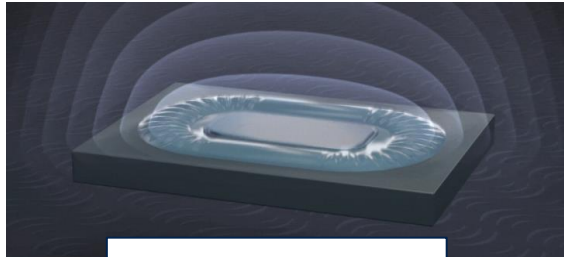


- Compared with other technologies, MEMS speakers offers:
 - Lightweight, smaller size and power consumption
 - Simpler and repeatable manufacturing

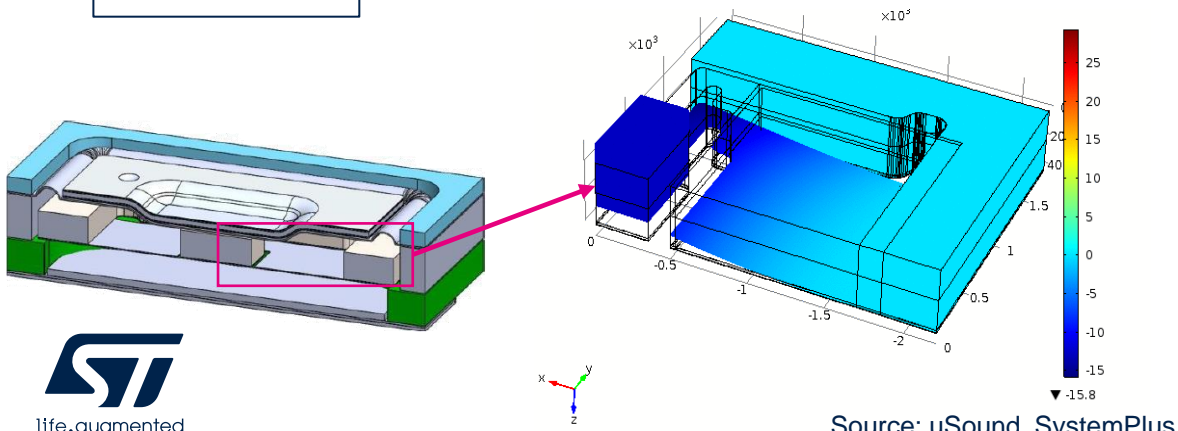
MEMS actuator + external membrane



MEMS die

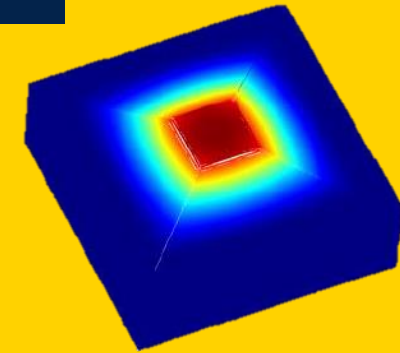


Packaged device



Source: uSound, SystemPlus

FULL SILICON



- Full silicon solution will further reduce the volume occupation and the complexity of the final device (no membrane needed)

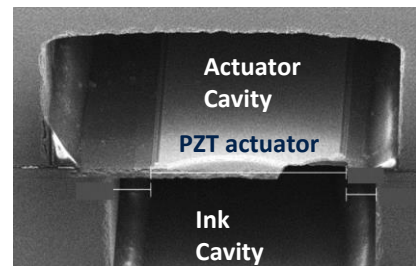
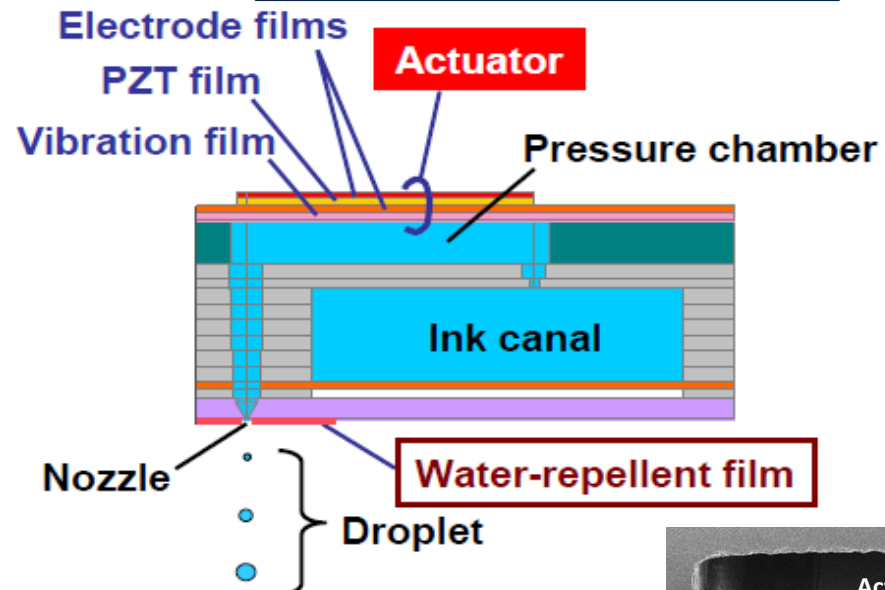
Microfluidics – Applications



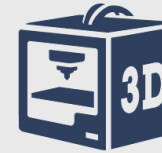
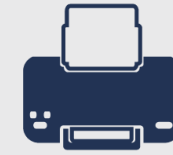
- **Microfluidics actuators:**

- Piezoelectric material used to shape the volume of a chamber and move fluids

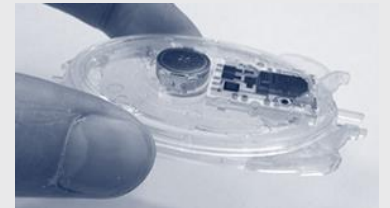
MEMS Inkjet Printheads



New applications



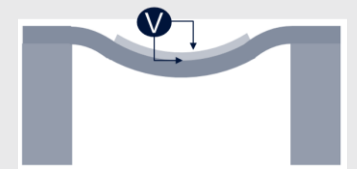
Smart Printing



MEMS pumps



Smart dosing

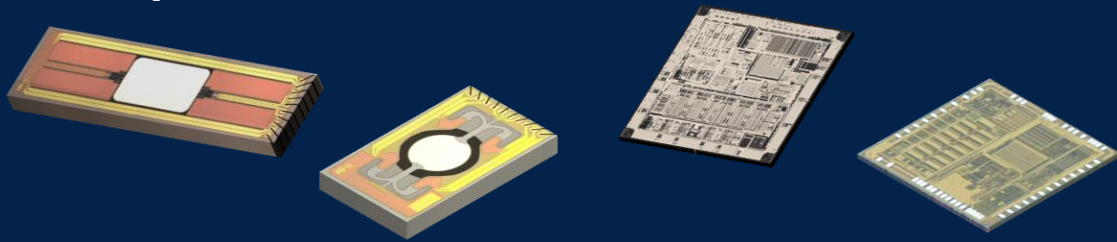


MEMS valves

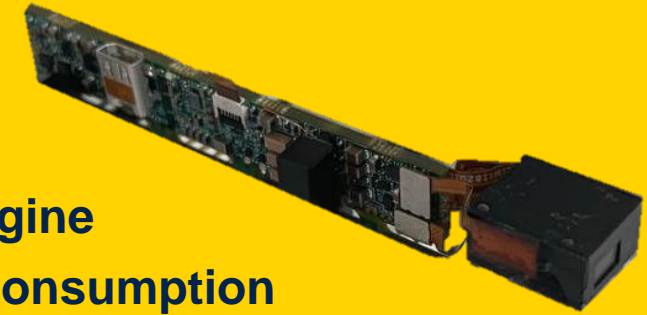
Takeaways

Takeaways

- ST MEMS mirrors and ASICs are key components to enable **all-day wearable AR glasses** thanks to **low power** and **small size**



- STAR1 Dev Kit system capable of:
 - **65deg FOV**
 - **1.5-10 lumens**
 - **720p resolution**
 - **0.7cc optical engine**
 - **350mW power consumption**

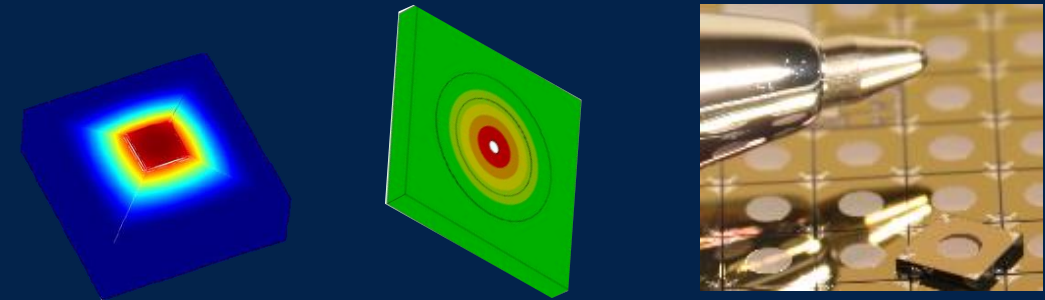


- Improvements to the P ϵ TRA piezoelectric technology platform will further improve MEMS performances:

- **Higher force**
- **Lower power**
- **Smaller footprint**
- **Higher resolution**



- **Flexible piezoelectric technology platform** suitable for different kinds of MEMS actuators



Our technology starts with You

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